II. Claim Amendments

Claims 1-11 (Cancelled)

12. (Currently Amended) A bipolar plate for fuel cells comprising:

a foil having a plurality of microstructures, said foil being at least partially conductive;

at least one channel structure, being an order of magnitude different than said microstructures, formed by said foil comprised of a plurality of channels wherein a substructure, being an order of magnitude different than said microstructures, is superimposed above the microstructures only between said channels, said substructure defining a fractal pattern with said microstructures;

whereby said channel structure selectively conveys a reactant; and whereby said plurality of microstructures are integrated into said foil, enhancing rigidity of said foil.

- 13. (Previously Presented) The bipolar plate as recited in claim 12, wherein each of said plurality of microstructures is generally shaped as a polygon.
- 14. (Previously Presented) The bipolar plate as recited in claim 12, wherein said plurality of microstructures cover a surface of said foil.
- 15. (Previously Presented) The bipolar plate as recited in claim 12, wherein said plurality of microstructures are formed by one of an embossing and an etching process.

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- 16. (Previously Presented) The bipolar plate as recited in claim 12, wherein said at least one channel structure is formed by one of an embossing and an etching process.
- 17. (Previously Presented) The bipolar plate as recited in claim 12, wherein each of said plurality of microstructures has a length generally between 1 micrometer (μm) and 500 micrometers (μm).
- 18. (Previously Presented) The bipolar plate as recited in claim 12, wherein said foil has a thickness of less than about 0.5 millimeters (mm).
- 19. (Previously Presented) The bipolar plate as recited in claim 12, wherein said channel structure forms a channel base, said channel base being shaped as a trough-like depression for draining away condensed reaction products.
- 20. (Previously Presented) The bipolar plate as recited in claim 12, wherein each of said microstructures including a recessed center forms a trough-like depression.
- 21. (Previously Presented) The bipolar plate as recited in claim 12, wherein said foil is hydrophobic.
- 22. (Currently Amended) The bipolar plate as recited in claim 12, wherein each of said microstructures includes at least one of said substructures substructure.

- 23. (Currently Amended) The bipolar plate as recited in claim 22, wherein said substructure has a length generally between [[1]] .1 micrometer (μm) and 50 micrometers (μm).
- 24. (Previously Presented) The bipolar plate as recited in claim 22, wherein said substructure includes a coating.
 - 25. (Withdrawn) A method of forming a bipolar plate comprising the steps of:

 forming a foil by one of an embossing and an etching process;

 shaping a channel structure onto said foil;

 integrating a plurality of microstructures in the form of polygons onto said

conveying a reactant by said channel structure; and
enhancing rigidity of said foil by including said plurality of
microstructures.

foil;

26. (Currently Amended) A bipolar plate for fuel cells comprising:

a foil having a plurality of microstructures formed onto a surface of said foil;

at least one channel structure, being an order of magnitude different than said

microstructures, formed by said foil comprised of a plurality of channels wherein a substructure,

being an order of magnitude different than said microstructures, is superimposed above the

microstructures only between said channels, said substructure defining a fractal pattern with said

microstructures;

whereby said channel structure selectively conveys a reactant to a proximate fuel cell; and

whereby said plurality of microstructures enhance rigidity of said foil.

- 27. (Previously Presented) The bipolar plate as recited in claim 25, wherein each of said plurality of microstructures is generally shaped as a polygon.
- 28. (Previously Presented) The bipolar plate as recited in claim 25, wherein said at least one channel structure is formed by one of an embossing and an etching process.